

The International Journal of Advanced Manufacturing Technology (2019) 100:2133
<https://doi.org/10.1007/s00170-018-2812-1>

CORRECTION



Correction to: Towards achieving nanofinish on silicon (Si) wafer by μ -wire electro-discharge machining

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Published online: 4 October 2018

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Correction to: Int J Adv Manuf Technol

<https://doi.org/10.1007/s00170-018-2692-4>

The authors would like to publish an Acknowledgement section.

Acknowledgments This work was supported by the Fundamental Research Grant (FRGS/1/2014/TK01/UIAM/02/2) sponsored by the Ministry of Higher Education Malaysia. Authors also acknowledge the research support provided by the International Islamic University Malaysia.

The online version of the original article can be found at <https://doi.org/10.1007/s00170-018-2692-4>

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